

AMENDMENT TRANSMITTAL LETTER

Docket No.
M4065.0073/P073Serial No.
09/123,430Filing Date
July 28, 1998Examiner
B. KebedeGroup Art Unit
2823

Applicant(s): Donald L. Yates

Invention: METHOD OF REDUCING SURFACE CONTAMINATION IN SEMICONDUCTOR WET-PROCESSING VESSELS

TO THE ASSISTANT COMMISSIONER FOR PATENTS

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

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CLAIMS AS AMENDED

	Claims Remaining After Amendment	Highest # Previously Paid	# Extra Claims Present	Rate	Additional F e
Total Claims	28	- 47 =	0	x \$18.00	
Independent Claims	14	- 8 =	6	x \$80.00	\$480.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$480.00

☒ Large Entity☐ Small Entity☐ No additional fee is required for amendment.☐ Please charge Deposit Account No. 4 - 1073 in the amount of _____
A duplicate copy of this sheet is enclosed.☒ A check in the amount of \$480.00 to cover the filing fee is enclosed.☒ The Commissioner is hereby authorized to charge and credit Deposit Account No. 4 - 1073 as described below. A duplicate copy of this sheet is enclosed.☒ Credit any overpayment.☒ Charge any additional filing or application processing fees required under 37 C.F.R. 1.16 and 1.17.

Thomas J. D'Amico

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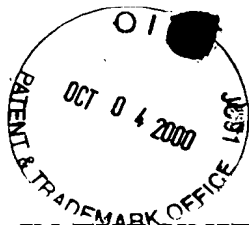
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Dated: October 4, 2000



PATENT
Docket No.: M4065.0073/P073

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Donald Yates

Serial No.: 09/123,430

Group Art Unit: 2823

Filed: July 28, 1998

Examiner: B. Kebede

For: METHOD OF REDUCING
SURFACE CONTAMINATION IN
SEMICONDUCTOR WET-
PROCESSING VESSELS

Assistant Commissioner for Patents
Washington, D.C. 20231

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AMENDMENT UNDER 37 C.F.R. § 1.116

Dear Sir:

In response to the Office Action dated July 5, 2000 (Paper No. 10), finally rejecting claims 1-10, 14-17, 20, 24, 26 and 27, please amend the above-identified U.S. patent application as follows:

IN THE CLAIMS:

Please cancel claims 28-43 and 45-47.

10/06/2000 AWONDAF1 00000072 09123430

Please amend the following claims: 01 FC:102

400.00 0P

1. (twice amended) A method for removing contaminants from a semiconductor processing bath for processing semiconductor wafers, said method comprising: